

Patent claims

1. An integrated read-only memory,
 - having selection transistors each having a drain connection,
 - having an electrode for feeding a voltage or a current,
 - having a layer between the drain connections and the electrode, the electrical resistance of which can be changed through the effect of a configuration voltage or a configuration current.
2. The read-only memory as claimed in claim 1,
 - in which the layer is formed as a common layer for linking the drain connections to the electrode, and
 - in which the electrical resistance of the layer can be changed locally.
- 20 3. The read-only memory as claimed in claim 1 or claim 2, in which the resistance of the layer can be switched over.
- 25 4. The read-only memory as claimed in one of the preceding claims, in which the resistance of the layer can be switched over between two resistance characteristic curves.
- 30 5. The read-only memory as claimed in one of the preceding claims,
 - having a read voltage applied to the layer or a read current fed to the layer within a defined voltage or current range in a read operation of the read-only memory, and
 - 35 • having a configuration voltage or a configuration current outside the voltage or current range provided for the read operation in a configuration operation of the read-only memory.

6. The read-only memory as claimed in one of the preceding claims, which is designed as a flash memory.

5 7. The read-only memory as claimed in one of the preceding claims, in which the selection transistors are arranged in an array.

10 8. The read-only memory as claimed in one of the preceding claims,

- having a source connection per selection transistor, and
- having a bit line that is electrically connected to at least one source connection.

15 9. The read-only memory as claimed in claim 8, in which the bit line is connected to a decoder circuit.

20 10. The read-only memory as claimed in claim 8 or claim 9, in which the bit line is accessible for an external connection.

11. The read-only memory as claimed in one of the preceding claims,

25 • having a gate connection per selection transistor, and

• having a word line that is electrically connected to at least one gate connection.

30 12. The read-only memory as claimed in claim 11, in which the word line is connected to a decoder circuit.

13. The read-only memory as claimed in claim 11 or claim 12, in which the word line is accessible for an
35 external connection.

14. The read-only memory as claimed in one of the preceding claims, in which the selection transistors have a planar construction in the substrate.
- 5 15. The read-only memory as claimed in one of claims 1 to 13, in which the selection transistors have a vertical construction in the substrate.
- 10 16. The read-only memory as claimed in one of the preceding claims, in which the layer is formed as a molecular layer.
17. The read-only memory as claimed in claim 16, in which the layer contains rotaxane.
- 15 18. The read-only memory as claimed in claim 16, in which the layer contains catenane.
19. The read-only memory as claimed in claim 16, in which the layer contains a bispyridinium compound.
- 20 20. The read-only memory as claimed in one of claims 1 to 15, in which the layer is formed as a dielectric.
- 25 21. The read-only memory as claimed in claim 20, in which the layer contains SrZrO₃.
22. The read-only memory as claimed in one of claims 1 to 15, in which the layer is formed as a polymer.
- 30 23. The read-only memory as claimed in claim 22, in which the layer contains 3-nitrobenzal malonitrile, 1,4-phenylenediamine complex.
- 35 24. The read-only memory as claimed in claim 22, in which the layer contains a chalcogenide compound.

25. A method for operating an integrated read-only memory as claimed in one of the preceding claims,

- in which in a read operation, a read voltage or a read current within a defined voltage or current range is applied to the layer, and
- in which, in a configuration operation, a configuration voltage or a configuration current outside the voltage or current range provided for the read operation is applied to the layer.

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26. A method for producing an integrated read-only memory,

- in which an array of selection transistors is produced using CMOS technology,
- in which drain contacts of the selection transistors are led to the surface of the arrangement,
- in which a layer is deposited whose electrical resistance can be changed through the effect of a configuration voltage or a configuration current,
- in which an electrode is arranged above the layer.

27. The method for producing an integrated read-only memory as claimed in claim 26, in which the layer is deposited as a common layer for linking the drain connections to the electrode above the selection transistors.

28. The method for producing an integrated read-only memory as claimed in claim 26 or claim 27, in which the selection transistors are produced in a front end process.

29. The method for producing an integrated read-only memory as claimed in one of claims 26 to 28, in which the layer is deposited in a back end process.

30. The method for producing an integrated read-only memory as claimed in one of claims 26 to 29, in which the selection transistors are constructed in planar fashion in the substrate.

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31. The method for producing an integrated read-only memory as claimed in one of claims 26 to 29, in which the selection transistors are constructed vertically in the substrate.

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32. The method for producing an integrated read-only memory as claimed in one of claims 26 to 31, in which the layer is formed as a molecular layer.

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33. The method for producing an integrated read-only memory as claimed in claim 32, in which the layer contains rotaxane.

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34. The method for producing an integrated read-only memory as claimed in claim 32, in which the layer contains catenane.

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35. The method for producing an integrated read-only memory as claimed in claim 32, in which the layer contains a bispyridinium compound.

36. The method for producing an integrated read-only memory as claimed in one of claims 26 to 31, in which the layer is formed as a dielectric.

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37. The method for producing an integrated read-only memory as claimed in claim 36, in which the layer contains SrZrO₃.

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38. The method for producing an integrated read-only memory as claimed in one of claims 26 to 31, in which the layer is formed as a polymer.

39. The method for producing an integrated read-only memory as claimed in claim 38, in which the layer contains a 3-nitrobenzal malonitrile, 1,4-phenylenediamine complex.

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40. The method for producing an integrated read-only memory as claimed in one of claims 26 to 31, in which the layer contains a chalcogenide compound.